

**RESPONSE UNDER 37 C.F.R. 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2811**

Attorney Docket No. 5649-1286

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re: Park et al.  
Serial No.: 10/828,596  
Filed: April 21, 2004  
For: METHODS OF FORMING METAL THIN FILMS, LANTHANUM OXIDE FILMS  
AND HIGH DIELECTRIC FILMS FOR SEMICONDUCTOR DEVICES USING  
ATOMIC LAYER DEPOSITION

Confirmation No.: 5520  
Group Art Unit: 2811  
Examiner: Ori Nadav

Date: September 25, 2008

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AFTER FINAL ACTION  
PURSUANT TO 37 C.F.R. § 1.116**

Sir:

This Amendment is responsive to the final Office Action dated July 25, 2008. Applicants respectfully request entry of this Amendment and allowance of the present application. Alternatively, Applicants respectfully request entry of this Amendment as narrowing the issues for further consideration.

It is not believed that any fee(s), including fees for additional claims, are required, beyond those that may otherwise be provided for in documents accompanying this submission. In the event, however, that any requests, petitions or extensions of time for the accompanying response are required to prevent abandonment of this application, Applicants submit that such an extension is also hereby petitioned for under 37 C.F.R. §1.136(a) and/or a request be granted pursuant to 37 C.F.R. §1.114. Any additional fees believed to be due in connection with this submission may be charged to our Deposit Account No. 50-0220, or any overpayment may be credited to the same.

**Amendments to the Claims** begin on page 2 of this document.

**Remarks** begin on page 12 of this document.

DO NOT ENTER: /O.N./